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APPLICANTS

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 This application is a DIV of 09/641,125 08/16/2000 PAT 6,645,676 *a, 2.*

**** FOREIGN APPLICATIONS *******
 JAPAN 11-232358 08/19/1999 *a, 2.*

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35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged <i>a, 2.</i> Examiner's Signature Initials				

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TITLE
 Electron beam exposure mask, electron beam exposure method, method of fabricating semiconductor device, and electron beam exposure apparatus

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